

PATENT
2342-0111P

IN THE U.S. PATENT AND TRADEMARK OFFICE

APPLICANT: Kazuyuki TOYODA et al.
APPL. NO.: 08/905,971
FILED: August 5, 1997
FOR: SUBSTRATE PROCESSING APPARATUS

GROUP: 1763
EXAMINER: R. Zervigon

Stamp:

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SUPPLEMENTAL AMENDMENT UNDER 37 C.F.R. §1.111

Assistant Commissioner for Patents
Washington, D.C. 20231

October 26, 2000

Sir:

Subsequent to the filing of the Amendment on September 27, 2000 in reply to the Office Action dated March 27, 2000, the following additional dependent claims and supplementary remarks are respectfully submitted in connection with the above-identified application.

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IN THE CLAIMS:

Please add the following new claims:

--33. A substrate processing apparatus as recited in claim 1, wherein the apparatus is configured to transfer a plurality of substrate at a time and to process a plurality of substrate at a time.

34. A substrate processing apparatus as recited in claim 1, wherein the apparatus is configured to transfer a plurality of substrate at a time and to process a plurality of substrate at a time.--

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